

FORM 1449* FORTY-FIFTH SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (Use several sheets if necessary)	Docket Number: 60001.0049US01/154685.01	Application Number: 09/841,265
	Applicant: Jeff Reynar	
	Filing Date: April 24, 2001	Group Art Unit: 2626

U.S. PATENT DOCUMENTS							
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	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	JP 08-272662	10.1996	Japan (w/ English language Abstract)				
	JP 2000-231566	08.2000	Japan (w/ English language Abstract)				
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		Shirowa, K., "iMac&iBook, Must-see for User, Full of Recommended Setting Methods and Specially Selected Tips, Mastering Mac OS9", MacPeople, ASCII Corporation, Japan, December 3, 1999, vol. 5, no. 24, p. 50 (in Japanese - no translation yet)					
		(Previously cited) Koyaku, H., "What is Brought to SQL Server 2000 by XML, Part 1: Function of XML Provided by SQL Server 2000", Enterprise Servers World, Vol. 3, No. 12, IDG Japan, Inc., December 1, 2000, pp. 42-53 (with English language translation)					
		U.S. Final Office Action dated January 22, 2009 cited in Application No. 10/366,141					

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EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
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		U.S. Office Action dated February 4, 2009 cited in Application No. 10/377,258					
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		European Summons to Attend Oral Proceedings dated February 26, 2009 cited in European Application No. 0301283.0-2211 (60001.0182EP01)					
		European Communication dated March 18, 2009 cited in European Application No. 04003683.2-2211 (60001.0216EP01)					
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27488

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